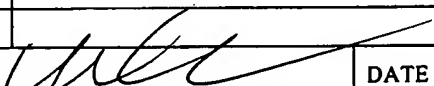


INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 1 OF 2		ATTY. DOCKET NO. P146-US		SERIAL NO. Not Yet Assigned			
		APPLICANT Robert Duboc, et al.					
		FILING DATE Herewith		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
ML	U.S Pub App No. 2003/0002019	1/2/03	Miller				
	U.S Pub App No. 2002/0056898	5/16/02	Lopes, et al.				
	U.S Pub App No. 2002/0063322	5/30/02	Robbins, et al.				
	6,300,294	10/9/01	Robbins, et al.				
	5,694,740	12/9/97	Martin, et al.				
	5,936,758	8/10/99	Fisher, et al.				
	5,610,438	3/11/97	Wallace, et al.				
ML	5,512,374	4/30/96	Wallace, et al.				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
ML	"Lubrication of Digital Micromirror Devices" Henck, Tribology Letters 3 (1997) 239-247 Micromotor Operation in a Liquid Environment" Dhuler, IEEE 1992 pgs 10-13						
ML	"Optimization of Lubricants fir silica Micromotors" Zarred, Sensors and Actuators A 46-47 (1995) 598-600 "Fabrication of packaged thin beam structures by an improved driving method" Masato Ohtsu, IEEE (1996) 0-7803-2985-6, pgs 228-233						
ML	"Operation of electrostatic micromotors in liquid environments" Mehran Mehregany, J. Micromech. Microeng. 2 (1992) 1-3 "Nanotribology and nanomechanics of MEMS devices", Nharad Bhushan, IEEE0-7803-298-5-6, pgs 91-98						
ML	"Micromotor dynamics in lubricating fluids" Keren Deng, J. Micromech. Microeng. 4 (1994) 266-269						
ML	"Stiction reduction processes for surface mciromachines" Roya Maboudian Tribology letters 3 (1997) 215-221						
ML	"Friction and Pull-off Force on Silicon Surface Modified by FIB" Ando IEEE 1996, 0-7803-2985-6/96, pgs 349-353						
ML	"Measurement of Micromoto Dynamics in Lubricating Fluids" Deng IEEE						
ML	"Friction and Wear studies on Lubricants and materials Applicablè to MEMS" Shigehisa Suzuki, IEEE 1991, pgs 143-147						
EXAMINER			DATE CONSIDERED 11/9/05				

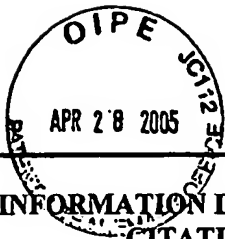
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 2 OF 2			ATTY. DOCKET NO. P146-US		SERIAL NO. Not Yet Assigned		
			APPLICANT Robert Duboc, et al.				
			FILING DATE Herewith		GROUP Not Yet Assigned		
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
ML	6,533,632	03/18/03	Dynka				
	6,259,551	07/10/01	Jacobs				
	6,664,779 B2	12/16/03	Lopes, et al.				
	5,293,511	03/08/94	Poradish, et al.				
	6,624,944 B1	09/23/03	Wallace, et al.				
ML	5,929,515	07/27/99	Greiff, et al.				
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
ML	Saes getters "A key Technology" www.saesgetters.com , 2 pgs						
EXAMINER				DATE CONSIDERED 11/23/05			

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INFORMATION DISCLOSURE CITATION APR 28 2005 PTO-1449 SHEET 1 OF 2		ATTY. DOCKET NO. P146-US		SERIAL NO. 10/810,076			
		APPLICANT Duboc et al.					
		FILING DATE 3/26/04		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	FILING DATE		
ml	2003/0064149	4/3/03	Miller				
	6,204,085	3/20/01	Strumpell, et al.				
	5,447,600	9/5/95	Webb				
	6,300,294	10/9/01	Robbins, et al.				
	6,086,726	7/11/00	Renk, et al.				
	6,475,570	11/5/02	Jacobs				
	2004/0100677	5/27/04	Huibers, et al.				
ml	2004/0125346	7/1/04	Huibers				
FOREIGN PATENT DOCUMENTS							
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
ml	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICTION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.						
	W. Robert Ashurst et al., VAPOR PHASE ANTI-STICTION COATINGS FOR MEMS, Pgs 1-6.						
ml	W. Robert Ashurst, et al., NANOMETER-THIN TITANIA FILMS WITH SAM-LEVEL STICKTION AND SUPERIOR WEAR RESISITANCE FOR RELIABLE MEMS PERFORMANCE, 4 pgs.						
	B.C. Bunker, et al., THE IMPACT OF SOLUTION AGGLOMERATION ON THE DEPOSITION OF SELF-ASSEMBLED MONOLAYERS, 2000 American Chemical Society, Pgs 7742-7751.						
ml	W. Robert Ashurst, et al., ALKENE BASED MONOLAYER FILMS AS ANTI-STICTION COATINGS FOR POLYSILICON MEMS, Berkeley Sensor & Actuator Center, 4 pgs.						
	S Imad-Uddin Ahmed, et al., USING SELF ASSEMBLED MONOLAYERS TO REDUCE FRICTION AND WEAR IN POLYSILICON BASED MEMS, 2000, Pgs. 1-18.						
EXAMINER	<i>[Signature]</i>		DATE CONSIDERED 4/23/05				

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		APPLICANT Duboc et al.					
		FILING DATE 3/26/04		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
ML	2004/0012838	1/22/04	Huibers				
	2004/0100594	5/27/04	Huibers, et al.				
	2004/0156090	8/12/04	Patel, et al.				
	5,835,256	11/10/98	Huibers				
	6,046,840	4/4/00	Huibers				
	6,844,959	1/18/05	Huibers, et al.				
	6,867,897	3/15/05	Patel, et al.				
	5,287,096	2/15/94	Thompson, et al.				
	5,939,785	8/17/99	Klonis, et al.				
ML	5,411,769	8/17/99	Hornbeck				
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EXAMINER				DATE CONSIDERED 4/23/05			

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